

In re Application of:

CHO, SEON-MEE

Application No.:

10800377

Filing Date:

03/11/2004

Title:

METHOD AND APPARATUS FOR UV EXPOSURE  
OF LOW DIELECTRIC CONSTANT MATERIALS FOR  
POROGEN REMOVAL AND IMPROVED  
MECHANICAL PROPERTIES

Direct to:

U.S. Patent and Trademark Office  
Mail Stop: **Duplicates**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450**NOTICE UNDER 37 CFR 1.251 – Pending Application**

Statement (check the appropriate box):

☐ The copy submitted with this reply is a complete and accurate copy of applicant's record of all of the correspondence between the Office and the applicant for the above-identified application (except for U.S. patent documents), and applicant is not aware of any correspondence between the Office and applicant for the above-identified application that is not among applicant's records.

☒ The copy of the paper(s) listed in the notice under 37 CFR 1.251 is/are a complete and accurate copy of applicant's record of such paper(s). *(copy submitted herewith)*

☐ The papers produced by applicant are applicant's complete record of all of the correspondence between the Office and the applicant for the above-identified application (except for U.S. patent documents), and applicant is not aware of any correspondence between the Office and the applicant for the above-identified application that is not among applicant's records.

☐ Applicant does not possess any record of the correspondence between the Office and the applicant for the above-identified application.

Oct. 28, 2005  
Date  
SignatureJeffrey K. Weaver  
Typed or printed name**A Copy of this notice should be returned with the reply.**

Burden Hour Statement: This collection of information is required by 37 CFR 1.251. The information is used by the public to reply to a request for copies of correspondence between the applicant and the USPTO in order to reconstruct an application file. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This form is estimated to take 60 minutes to complete. This time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, Virginia 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450.

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re application of: Cho et al.

Atty Docket No.: NOVLP089/NVLS-  
002886/002887

Application No.: 10/800,377

Examiner: UNASSIGNED

Filed: March 11, 2004

Group: 2812

Title: METHOD AND APPARATUS FOR UV  
EXPOSURE OF LOW DIELECTRIC CONSTANT  
MATERIALS FOR POROGEN REMOVAL AND  
IMPROVED MECHANICAL PROPERTIES

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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on October 28, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

  
Leslie Russell

**RESPONSE TO NOTICE UNDER 37 CFR 1.251 – PENDING APPLICATION**

Commissioner for Patents  
Mail Stop: Duplicates  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Notice Under 37 CFR 1.251 mailed September 26, 2005, enclosed is a copy of the original Information Disclosure statement and all foreign references and NPLS originally mailed June 20, 2005 for the above-identified patent application.

Accordingly, it is believed that no fees are due in connection with the filing of this response. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP089).

Respectfully submitted,

BEYER WEAVER & THOMAS, LLP

  
Jeffrey K. Weaver

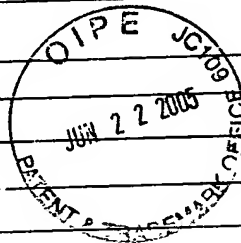
Registration No. 31,314

P.O. Box 70250  
Oakland, CA 94612-0250  
(510) 663-1100

Docket #	NOVLP089/NVLS-2887	By:	JKW/th	Date of this mailing:	June 20, 2005
Appl'n #:	10/800,377	Filing Date:	March 11, 2004	Express Mail #	N/A
Inv(s)	Cho et al.				
Title:	METHOD AND APPARATUS FOR UV EXPOSURE OF LOW DIELECTRIC CONSTANT MATERIALS FOR POROGEN REMOVAL AND IMPROVED MECHANICAL PROPERTIES				

The following have been received in the U.S. Patent Office on the date stamped hereon:

Item	Description	# Pgs
1.	Information Disclosure Statement w/cert of mailing	01
2.	PTO Form 1449	05
3.	Copies of cited references (41)	
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BEYER WEAVER & THOMAS, LLP  
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 DATE: 6/30 BY: CN

